

Martina Lattemann

List of Publications by Year in descending order

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13
papers

1,179
citations

1163117

8
h-index

1281871

11
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14
all docs

14
docs citations

14
times ranked

1033
citing authors

#	ARTICLE	IF	CITATIONS
1	MD study of C diffusion in WC/W interfaces observed in cemented carbides. International Journal of Refractory Metals and Hard Materials, 2019, 85, 105054.	3.8	6
2	Magnetic Saturation: Understanding Quality Control of Hard Metals in Industry - A Quantum Mechanics Approach (Adv. Theory Simul. 6/2019). Advanced Theory and Simulations, 2019, 2, 1970021.	2.8	0
3	Influence of characteristic properties of PCD grades on the wear development in turning of $\hat{1}^2$ -titanium alloy (Ti5Al5V5Mo3Cr). Wear, 2019, 426-427, 1594-1602.	3.1	15
4	Understanding Quality Control of Hard Metals in Industry - A Quantum Mechanics Approach. Advanced Theory and Simulations, 2019, 2, 1900035.	2.8	2
5	Quantum mechanics basis of quality control in hard metals. Acta Materialia, 2019, 169, 1-8.	7.9	4
6	High resolution STEM investigation of interface layers in cemented carbides. International Journal of Refractory Metals and Hard Materials, 2018, 72, 135-140.	3.8	14
7	Specific carbide substrate design to enhance tool performance in machining of Ti5553. Procedia CIRP, 2018, 77, 598-601.	1.9	9
8	A consistent path for phase determination based on transmission electron microscopy techniques and supporting simulations. Micron, 2018, 115, 41-49.	2.2	0
9	Electronic origin of structure and mechanical properties in Y and Nb alloyed Ti-Al-N thin films. International Journal of Materials Research, 2011, 102, 735-742.	0.3	38
10	Microstructure Evolution During Spark Plasma Sintering of Metastable (ZrO ₂ -3 mol%) Tj ETQq0 0 0 rgBT /Overlock 10 T the American Ceramic Society, 2010, 93, 2864-2870.	3.8	20
11	Transition between the discharge regimes of high power impulse magnetron sputtering and conventional direct current magnetron sputtering. Plasma Sources Science and Technology, 2009, 18, 045008.	3.1	79
12	Cross-field ion transport during high power impulse magnetron sputtering. Plasma Sources Science and Technology, 2008, 17, 035021.	3.1	106
13	Ionized physical vapor deposition (IPVD): A review of technology and applications. Thin Solid Films, 2006, 513, 1-24.	1.8	886